L Number	Hits	Search Text	DB	Time stamp
1	2	(electron adj beam adj microscope) and ((low adj energy adj electron adj microscope) or LEEM)	USPAT; US-PGPUB;	2004/09/27 14:03
2	21	(((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection) and review	EPO; JPO; IBM_TDB USPAT; US-PGPUB;	2004/09/27 14:03
4	0	(((((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection) and review) and (continuous\$3 near4 stage)) and (on near2 fly)	EPO; JPO; IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/09/27 14:06
3	. <b>17</b>	((((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection) and review) and (continuous\$3 near4 stage)	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/09/27 14:14
-	266	electron adj beam adj microscope	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/05/06 10:30
-	138	(electron adj beam adj microscope) and substrate	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/05/06 10:31
-	74	((electron adj beam adj microscope) and substrate) and wafer	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/05/06 10:31
<b>-</b>	67	(((electron adj beam adj microscope) and substrate) and wafer) and semiconductor	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/05/06 10:32
-	35	((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/05/06 10:33
-	2	(electron adj beam adj microscope) and ((low adj energy adj electron adj microscope) or LEEM)	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/09/27 14:02
-	2	(((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection) and ((low adj energy adj electron adj microscope) or LEEM)	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/05/06 10:46
-	20	(((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection) and review	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/09/27 14:03
-	2	((((((electron adj beam adj microscope) and substrate) and wafer) and semiconductor) and inspection) and review) and ((low adj energy adj electron adj microscope) or LEEM)	IBM_TDB USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2004/05/19 17:29